

Electronic Patent Application Fee Transmittal

Application Number:	10781247			
Filing Date:	18-Feb-2004			
Title of Invention:	System and method of CVD chamber cleaning			
First Named Inventor/Applicant Name:	Chou San Nelson Loke			
Filer:	Katsuhiro Arai/Keiko Kinoshita (KOA)			
Attorney Docket Number:	ASMJP.145AUS			
Filed as Large Entity				
Utility Filing Fees				
Description	Fee Code	Quantity	Amount	Sub-Total in USD(\$)
Basic Filing:				
Pages:				
Claims:				
Claims in excess of 20	1202	7	50	350
Miscellaneous-Filing:				
Petition:				
Patent-Appeals-and-Interference:				
Post-Allowance-and-Post-Issuance:				
Extension-of-Time:				

Description	Fee Code	Quantity	Amount	Sub-Total in USD(\$)
Miscellaneous:				
Total in USD (\$)				350